## IN THE CLAIMS:

Please amend Claims 1 to 7 as shown below.

- 1. (Currently Amended) A composition for forming a piezoelectric <u>film</u>, <u>comprising containing</u> a dispersoid obtained from <u>a</u> metallic compound, wherein the content of hafnium contained in the <u>said</u> composition is 3,000 ppm or less.
- 2. (Currently Amended) A composition for forming a piezoelectric <u>film</u> according to claim 1, wherein said metallic compound is at least one of metallic compound selected from the group consisting of organometallic alkoxides, organometallic complexes, metal organic <u>salts</u> salts, and metal hydroxides.
- 3. (Currently Amended) A composition for forming a piezoelectric film according to claim 1, wherein the content of hafnium contained in said composition is 2,000 ppm or less.
- 4. (Currently Amended) A method for producing a piezoelectric film comprising the steps of:

coating a substrate with a composition for forming [[a]] said piezoelectric film, to form a coating film, said composition containing a dispersoid obtained from a metallic compound, in which and the content of hafnium in said composition being [[is]] 3,000 ppm or less, to form a coating film;

drying the coating film; and sintering the dried coating film to obtain [[a]] said piezoelectric film.

- 5. (Currently Amended) A piezoelectric element comprising a piezoelectric film held between a lower electrode and an upper electrode, wherein the <u>said</u> piezoelectric film is produced by the method of claim 4.
- 6. (Currently Amended) A piezoelectric element according to claim 5, wherein the content of hafnium contained in said piezoelectric film held between the lower electrode and the upper electrode is 3,000 ppm or less.
- 7. (Currently Amended) An ink jet recording head comprising a pressure chamber communicating with an ink discharge port, a diaphragm provided in correspondence with the said pressure chamber, and the piezoelectric element of claim 5 provided in correspondence with the diaphragm, wherein an ink in the said pressure chamber is discharged through said ink discharge port by a change of volume in said pressure chamber caused by the piezoelectric element.